

Reference No.: P 9 9 T O 2 1 6



Mailing No.:250112 1/

Mailing Date: July 22, 2003

(TRANSLATION)

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NOTICE OF GROUND FOR REJECTION

Re: Patent Application No.11-351546

Drafting Date: July 14, 2003

From: KITAMURA Akihiro, Examiner of Patent Office 8019 4Q00

To: Junzo OGAWA, Representative for Applicant of Patent (and one other)

Applied clauses: Section 29 (2)

<< FINAL >>

This application is deemed to be rejected on the following grounds. If the applicant has any objection against this, an argument must be filed within 60 days from the mailing date of this notice.

GROUND

The inventions relating to the following claims of this application are found to be easily inventible to the person of ordinary knowledge in the art, based on the inventions disclosed in the paper publications distributed in Japan or in the foreign countries prior to the filing date of this application, and the present application cannot be allowed by virtue of the provisions of Sec.29 (2) of Patent Law.

(See the list below for the cited references)

Claims 1-11, Cited literatures 1-7 (hereinafter referred to as citations 1-7)

(Remarks)

Cited literatures 1-4 were cited in the last Office Action. Citations 5-7 are newly cited.

★ Citation 5 describes a means for coating the inner wall of a plasma etching device with a material having a small erosion rate (claim 7), and illustrates Y_2O_3 as the material (claim 8).

✍ Citation 6 describes an anticorrosion member which composes the region exposed to plasma of a Periodic Table 3a element compound (claim), illustrates Y_2O_3 as the compound (Paragraph 0013), and describes that the surface of a substrate is coated with the compound (Paragraph 0014).

Citation 7 describes a sprayed film having an gradient composition (claim).

The surface of a substrate spray-coated with an anticorrosion film in the inner member of a plasma treating vessel has been known as described in Citation 1. Citation 2 discloses that Y_2O_3 is useful as the anticorrosion member, and Citations 5-6 disclose the use of Y_2O_3 as the anticorrosion film, so that the point of coating with a Y_2O_3 sprayed film in the present invention is a means easily carried out by those skilled in the art.

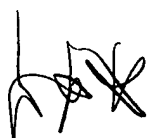
Moreover, the porosity is specified by the amendment. However, it has been known that the more minute the anticorrosion film on the surface of a substrate is, the ~~more desirable in the point of preventing invasion of corrosive gas and film peeling~~, and it has been also known that the sprayed film is porous. Even if the porosity "5-10%" specified in the present invention is not disclosed in each citation, to what an extent the porosity of an anticorrosion film can be allowed is the matter properly selected in accordance with conditions such as corrosion resistance of a film, atmosphere in a plasma treating vessel and the like.

Furthermore, the matters relating to the undercoat and the intermediate layer described in claims 2-7 and 9-11 are as explained in the last Office Action. The sprayed film having a gradient concentration can suitably be carried out as described in Citation 7.

In addition, the applicant argues differences of the present invention from Citation 1 in the argument, but Citation is simply shown as an example of conventional technique for spray-forming alumina on the surface of a substrate of an inner member of a plasma treating vessel, and is not cited a method of forming a new aluminum oxide argued by the applicant. Such conventional technique is disclosed in JP-A-8-339895, JP-A-64-39728 and others.

LIST OF REFERENCES

1. JP-A-7-176524
2. JP-A-10-45461
3. JP-A-6-142822
4. JIS Using Series, "Spraying Technique Manual", page 95
(October 30, 1998, Japanese Standard Association)
5. JP-A-8-37180
6. JP-A-10-4083
7. JP-A-5-238859



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GROUND FOR FINAL REJECTION

1. This notice is to inform the applicant of grounds for rejection which is needed to be notified in response to the amendment to the First Office Action.

• Contact Information:

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